

Appl. No. 10/077,072  
Amdt. dated 08/19/2003  
Reply to Office action of 06/19/2003



PATENT

#12/C  
9600  
9503

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: )  
FISCHER et al. ) Group Art Unit: 2821  
Application No: 10/077,072 ) Examiner: LEE, Wilson  
Filed: February 14, 2002 ) Atty. Docket No: P0877  
For: A PLASMA PROCESSING APPARATUS ) Date: August 19, 2003  
AND METHOD FOR CONFINING AN RF )  
PLASMA UNDER VERY HIGH GAS FLOW )  
AND RF POWER DENSITY CONDITIONS )

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on August 19, 2003

Signed: Sharon Tillery  
Sharon Tillery

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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**PRELIMINARY AMENDMENT**

Dear Sir:

In response to the Final Office Action mailed on June 19, 2003, please enter the following amendments and remarks in the above-identified patent application:

**Amendments to the specifications** begin on page 2.

**Amendments to the claims** are reflected in the listing of claims, which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 8 of this paper.